



## IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Application of:

Shin-itsu TAKEHASHI et al.

Group Art Unit:

Serial No.: 10/088,264

Examiner:

Filed: March 18, 2002

For: THIN FILM TRANSISTOR AND METHOD FOR FABRICATING THE SAME

## SECOND PRELIMINARY AMENDMENT

Commissioner for Patents Washington, D. C. 20231

Sir:

Prior to examination of the above-identified application, please amend this application as follows:

## IN THE CLAIMS:

Please amend claims 1-54 as follows:

 (Amended) A method for fabricating an LDD thin film transistor, comprising:

forming a semiconductor layer on the substrate;

forming a metal film on the semiconductor layer;

PLEASE ACCEPT THIS AS AUTHORIZATION TO DEBIT OR CREDIT FEES TO DEP. ACCT. 16-0331 PARKHURST & WENDEL